

**AMENDMENTS TO THE CLAIMS**

**This listing of claims will replace all prior versions and listings of claims in the application:**

**LISTING OF CLAIMS:**

Claims 1-7. (canceled).

8. (currently amended): A method for manufacturing an organic electroluminescent device, comprising the steps of:

forming a conductive layer on an insulating substrate;

forming a photoresist pattern layer having a plurality of striped elements along a first direction on said conductive layer;

etching said conductive layer by a dry etching process using a first plasma gas and using said photoresist pattern layer as an etching mask in a chamber to form striped lower electrodes;

depositing an insulating layer on said photoresist pattern layer and on said insulating substrate between said lower electrodes by a plasma deposition process using a second plasma gas in said chamber;

performing a lift-off operation upon said photoresist pattern layer to remove said photoresist pattern layer and a part of said insulating layer on said photoresist pattern layer;

forming at least one organic thin film layer including an emitting layer on said insulating layer and said lower electrodes; and

forming a plurality of striped upper electrodes on said organic thin film layer along a second direction different from said first direction.

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9. (original): The method as set forth in claim 8, wherein a condition for introducing said first plasma gas is the same as a condition for introducing said second plasma gas.

10. (original): The method as set forth in claim 9, wherein each of said first and second plasma gas includes hydrocarbon gas.

11. (original): The method as set forth in claim 8, wherein a condition for introducing said first plasma gas is different from a condition for introducing said second plasma gas.

12. (original): The method as set forth in claim 11, wherein said first plasma gas includes halogen gas, and said second plasma gas includes hydrocarbon gas.

13.(original): The method as set forth in claim 8, wherein said lower electrodes are anodes and said upper electrodes are cathodes.

14. (original): The method as set forth in claim 13, further comprising a step of forming a hole-transporting layer between said lower electrodes and said emitting layer.

15. (original): The method as set forth in claim 13, further comprising a step of forming an electron-transporting layer between said emitting layer and said upper electrodes.

16. (original): The method as set forth in claim 8, wherein said insulating substrate is transparent and said lower electrodes comprise transparent conductive layers.

17. (original): The method as set forth in claim 16, wherein said transparent conductive layers comprise indium tin oxide.

18. (original): The method as set forth in claim 8, wherein said first direction is approximately normal to said second direction.

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19. (original): The method as set forth in claim 8, wherein said insulating layer comprises amorphous carbon.

20. (currently amended): A method for manufacturing an organic electroluminescent device, comprising the steps of:

forming a conductive layer on an insulating substrate;

forming a photoresist pattern layer having a plurality of striped elements along a first direction on said conductive layer;

etching said conductive layer by a dry etching process using gas including hydrocarbon gas and using said photoresist pattern layer as an etching mask in a chamber to form striped lower electrodes, and subsequently depositing an insulating layer on said photoresist pattern layer and on said insulating substrate between said lower electrodes by a plasma deposition process using said gas including hydrocarbon gas in said chamber;

performing a lift-off operation upon said photoresist pattern layer to remove said photoresist pattern layer and a part of said insulating layer on said photoresist pattern layer,

forming at least one organic thin film layer including an emitting layer on said insulating layer and said lower electrodes; and

forming a plurality of striped upper electrodes on said organic thin film layer along a second direction different from said first direction.

21. (currently amended): A method for manufacturing an organic electroluminescent device, comprising the steps of:

forming a conductive layer on an insulating substrate;

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forming a photoresist pattern layer having a plurality of striped elements along a first direction on said conductive layer;

etching said conductive layer by a dry etching process using a gas including halide gas and using said photoresist pattern layer as an etching mask in a chamber to form striped lower electrodes;

depositing an insulating layer on said photoresist pattern layer and on said insulating substrate between said lower electrodes by a plasma deposition process using a gas including hydrocarbon gas in said chamber;

performing a lift-off operation upon said photoresist pattern layer to remove said photoresist pattern layer and a part of said insulating layer on said photoresist pattern layer;

forming at least one organic thin film layer including an emitting layer on said insulating layer and said lower electrodes; and

forming a plurality of striped upper electrodes on said organic thin film layer along a second direction different from said first direction.